

Application No.: 10/007,502  
Amendment dated: September 29, 2003  
Reply to Office Action of April 29, 2003

This listing of claims will replace all prior versions and listings of claims in this application:

a.) Listing of Claims

1. (currently amended) A method for fabricating optical elements, comprising:  
forming topographic features on a surface of an optical element substrate;  
mechanically polishing the surface of the substrate to modify the features to produce a curved optical surface of the optical element; and  
dicing the substrate into the optical elements.
2. (original) A method as claimed in claim 1, wherein the step of forming the topographic features comprises forming blind holes into the substrate
3. (original) A method as claimed in claim 1, wherein the step of forming the topographic features comprises forming blind holes, having mesa profiles, into the substrate.
4. (original) A method as claimed in claim 1, wherein the step of forming the topographic features comprises forming a feature projecting from the substrate.
5. (original) A method as claimed in claim 1, wherein the step of forming the topographic features comprises forming mesas in the substrate.
6. (original) A method as claimed in claim 1, wherein the step of forming the topographic features comprises etching a blind hole into the substrate to a depth of a material layer.
7. (original) A method as claimed in claim 1, wherein the step of forming the topographic features comprises etching blind holes into the substrate in a timed process.
8. (original) A method as claimed in claim 1, wherein the step of polishing the surface comprises performing chemical mechanical polishing of the surface.

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9. (original) A method as claimed in claim 1, further comprising optically coating the surface after the polishing step.
10. (original) A method as claimed in claim 9, wherein the step of optically coating the surface comprises depositing a highly reflective layer on the surface.
11. (original) A method as claimed in claim 9, wherein the step of optically coating the surface comprises depositing an antireflective layer on the surface.
12. (original) A method as claimed in claim 1, further comprising optically coating the surface after the polishing step and before the dicing step.
13. (original) A method as claimed in claim 1, wherein the step of dicing the substrate comprises sawing the substrate.
14. (original) A method as claimed in claim 1, wherein the step of dicing the substrate comprises cleaving the substrate.
15. (new) A method as claimed in claim 1, wherein the step of forming the topographic features on the surface of the optical element substrate comprises forming the features on silicon or gallium phosphide wafer material.